

29. A substrate processing apparatus as recited in claim 14, wherein the apparatus is configured to transfer a plurality of substrates and to process a single substrate at a time.

30. A substrate processing apparatus as recited in claim 14, wherein the apparatus is configured to transfer and process a single substrate at a time.

15
cont

31. A substrate processing apparatus as recited in claim 14, wherein the apparatus is configured to transfer a single substrate and to process a plurality of substrates at a time.

32. A substrate processing apparatus as recited in claim 14, wherein the apparatus is configured to transfer a plurality of substrates and to process a single substrate at a time.--

REMARKS

Reconsideration and allowance in view of the foregoing amendments and the following remarks are respectfully requested. Claims 1-32 are pending in the application, claims 27-32 having been added by this amendment. Claims 1 and 14 are independent.

Summary of Examiner Interview

Initially, Applicant's representative wishes to thank Examiner Zervigon for his time at the interview of August 16, 2000, the content of which is summarized below.

Prior to the interview, we faxed the Examiner proposed discussion points to expedite the interview process. The Examiner has primarily focused attention on Fig. 4 of Tateishi et al.